

9/2003 10/018,709

U	P	T	P	Document ID	Issue Date	Pages	Title	Current OR	Current XRef Retrieval C	Inventor	S	C	
<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020112962 A1	20020822	10	Oxidising electrolytic method for obtaining a	205/102	204/230.6	Beauvir, Jacques	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 5201492 A	19930413		Metal diaphragm for diaphragm-type valve	251/331	92/103M	Beauvir, Jacques	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 4941504 A	19900717		Manual fluid-control valve with limited closing	137/524	137/556.3; 251/297;	Beauvir, Jacques	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>

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Drafts Pending Active L1: (3) "Beauvir Jacques".in. Failed Saved Favorites Tagged (0) UDC Queue Trash

Search List Boves Queue Clear DB: USPAT-USPTUB Default Order: OR "Beauvir Jacques".in.

BRS term BRS term Image Text HTML

Application: EAST NUM

New case Document 0034 pat2 10018703 10018703 10018703 10018703 New cases 0034 pat3 Changes Expiring In-box Mail

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Document ID	Pages	U	S	C	P	Kind	Codes	Source
1 US 6620303 B2	9							USPAT
2 US 6043681 A	25							USPAT
3 US 5603615 A	10							USPAT
4 US 5486280 A	7							USPAT
5 US 5470673 A	22							USPAT
6 US 5141602 A	27							USPAT
7 US 4789437 A	14							USPAT

US-PAT-NO: 5141602

DOCUMENT-IDENTIFIER: US 5141602 A

TITLE: High-productivity method and apparatus for making customized interconnections

----- RWIC -----

Detailed Description Text - DCTX (39):

Electronic controller 88 comprises a microcomputer 101 with a data acquisition board 102, which controls an ac waveform generator 103, and an electrically controlled constant voltage or constant current amplifier 104. An ac ammeter 105 and an ac voltmeter 106, measures the voltage and the current on line 99.

Detailed Description Text - DCTX (40):

Acquisition board 102 couples a digital output signal indicative of frequency from digital output device 111 over lead 108 to an input of ac waveform generator 103. Acquisition board 102 couples a digital output signal indicative of amplifier mode (voltage or current) from digital output device 111 over lead 109 to an input of ac voltage/current power amplifier.

Detailed Description Text - DCTX (44):

In FIGS. 9A and 9B like references are used for functions corresponding to the apparatus of FIG. 8. The crystal oscillator 123, divide by four frequency divider 124 and programmable frequency divider 125 provide a stable source of frequencies between 1 KHz and 64 KHz. The frequency can be set by either the computer controller 121 or by switches. The voltage reference 131 accepts a voltage provided over lead 112 by the controller 121 or can generate a voltage set locally that varies between 1 mV and 10 V. The unity gain inverting amplifier 132 takes the reference voltage and generates a negative voltage of the same magnitude. The waveform generator 136 creates a square wave whose peak amplitude is equal to the output of the voltage reference 131 and whose frequency is set by the output of the programmable frequency divider 125. The square wave has an average value of 0 Volts. The voltage/current mode select circuit 137 determines whether the self induced repair is occurring in a constant voltage or constant current regime by the signals on lead 109. In the constant voltage mode the output from the waveform generator 136 is applied to the power amplifier 138. The constant current mode will be addressed later in this document. The power amplifier 138 is a unity gain amplifier capable of a peak output voltage of 10 Volts and a peak output current of 2.5 Amps. The current detector 139 senses the current delivered to the defect, line 99, and has an output voltage proportional to the current. This signal is precision full wave rectified by the full wave rectifier 145 and filtered by lowpass filter 147 to provide a voltage proportional to the average current through the defect. This average current is displayed on a digital voltmeter 149 as well as being fed back over lead 116 to the computer controller 121 and difference amplifier 143. In a similar manner, the voltage across the defect is passed through a full wave rectifier 146 and lowpass filter 148 to obtain a voltage equal to the average value of the defect voltage. This signal is displayed on digital voltmeter 150 and fed back to the computer controller 121.

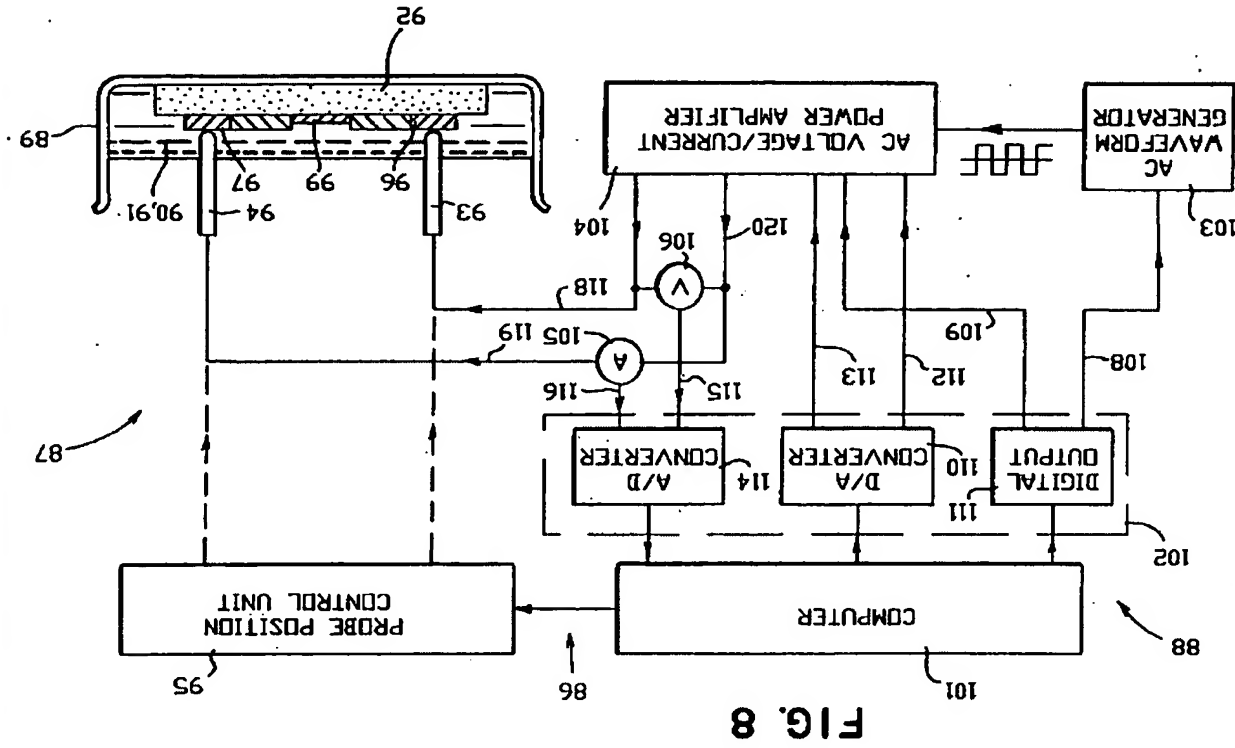


FIG. 8

Document ID	Pages	U	S	C	P	Kind Codes	Source
1 US 6322674 B1	34	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT
2 US 6139703 A	35	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT
3 US 6004440 A	36	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT
4 US 5695630 A	7	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT
5 US 5336379 A	7	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT
6 US 5287060 A	8	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT
7 US 5091152 A	11	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT

US-PAT-NO: 6322674

DOCUMENT-IDENTIFIER: US 6322674 B1

TITLE: Cathode current control system for a wafer electroplating apparatus

----- KWIC -----

Detailed Description Text - DCTX (11):

In the feedback system 185, a current monitor circuit 190 monitors the current flowing through the respective segment 130 and provides a signal indicative of the magnitude of the current to a central processing unit 195. The control processing unit 195, in turn, provides a feedback signal to a bias control circuit 200 that generates an output voltage therefrom to the inputs of comparator 180. Comparator 180 uses the signal from the bias control circuit 200 and, further, from a plating waveform generator 205 to generate the drive signal to the gate terminals of the FETs 170 and 175.

Current US Original Classification - CCOR (1):

204/212

Current US Cross Reference Classification - CCXR (1):

204/218

Current US Cross Reference Classification - CCXR (2):

204/242

United States Patent

Bernier et al.

(10) Patent No.: US 6,322,674 B1
(45) Date of Patent: Nov. 27, 2001(34) CATHODE CURRENT CONTROL SYSTEM
FOR A WAFER ELECTROPLATING
APPARATUS5,421,987 • 6/1995 Tzanavaras 205/133
6,001,235 • 12/1999 Aiken et al. 205/137

• cited by examiner

(75) Inventors: Robert W. Bernier, Eagle, ID (US);
Joseph J. Patula, Jr., San Jose, CA
(US); Robert Hitzfeld, San Jose, CA
(US); Richard Contreras, San Jose,
CA (US); Andrew Chiu, Milpitas, CA
(US)Primary Examiner—Donald R. Valentine
Assistant Examiner—Erica Smith-Hicks
(74) Attorney, Agent, or Firm—Poli & Associates, L.L.C.
(57) ABSTRACT(73) Assignee: Samticon, Inc., Kalispell, MT (US)
(*) Notice: Subject to any disclaimer, the term of this
patent is extended or adjusted under 35
U.S.C. 154(b) by 0 days.

(21) Appl. No.: 09/440,761

(22) Filed: Nov. 16, 1999

Related U.S. Application Data

(62) Division of application No. 08/933,450, filed on Sep. 18,
1997, now Pat. No. 6,004,440.(51) Int. Cl.⁷ C25D 17/00

(52) U.S. Cl. 204/212; 204/218; 204/242

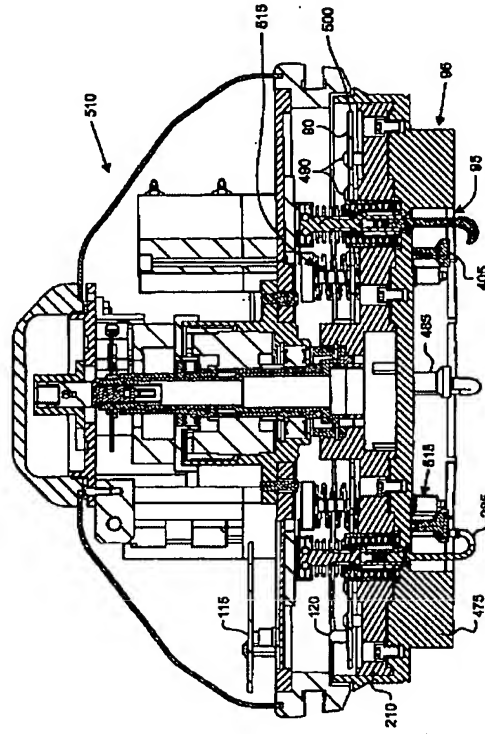
(58) Field of Search 204/212, 218,
204/242

References Cited

U.S. PATENT DOCUMENTS

4,304,641 • 12/1981 Gradia et al. 204/23

8 Claims, 28 Drawing Sheets



Document ID	Pages	U	S	C	P	Kind Codes	Sub
1 US 6322674 B1	34	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
2 US 6139703 A	35	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
3 US 6004440 A	36	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
4 US 5695630 A	7	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
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6 US 5287060 A	8	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
7 US 5091152 A	11	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT

US-PAT-NO: 5091152

DOCUMENT-IDENTIFIER: US 5091152 A

TITLE: Apparatus for electrically destroying targeted organisms in fluids

----- RWIC -----

Detailed Description Text - DETX (11):

A waveform generator 6, and a current regulator 8 are provided. The outputs of the waveform generator 6 and the current regulator 8 are supplied to an amplifier 7.

Detailed Description Text - DETX (12):

The waveform generator 6 is capable of providing a variable frequency output in a sine, square, pulsed negative-pulsed positive triggered, or saw-tooth waveform output 12, so that the targeted organism in inner area 33 and outer area 34, as shown in FIG. 2, can be destroyed.

Detailed Description Text - DETX (15):

As shown in FIG. 1B, a power supply 17 is provided which is capable of AC or DC operation, or in an uninterrupted configuration. The power output path to the waveform generator 6, the current regulator 8 and the power amplifier 7 are shown as 14.

Detailed Description Text - DETX (25):

FIGS. 6A and 6B show a second embodiment of the present invention. In this embodiment, the power supply 17, waveform generator 6, current regulator 8, amplifier 7 and transformer 5 are configured as shown in FIG. 1, except that the output of the transformer 5 is connected to the chamber in a single ended output arrangement with the center tap (at 10 and 11) not used. This embodiment is for static sterilization purposes using a two electrode chamber.

Claims Text - CUTX (9):

A.C. current waveform generator means for generating a plurality of waveforms with variable frequency and magnitude;

Claims Text - CUTX (11):

amplifier means, connected to receive the outputs of said waveform generator means and said current regulator means, for providing an amplified current;

Claims Text - CUTX (12):

power supply means for supplying power to said waveform generator means, said current regulator means, said amplifier means and said transformer means; and

Claims Text - CUTX (14):

FIG. 4

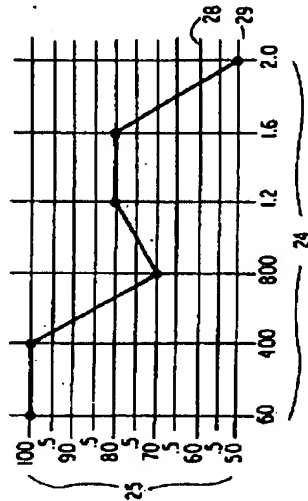


FIG. 5

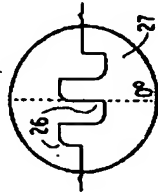


FIG. 6A

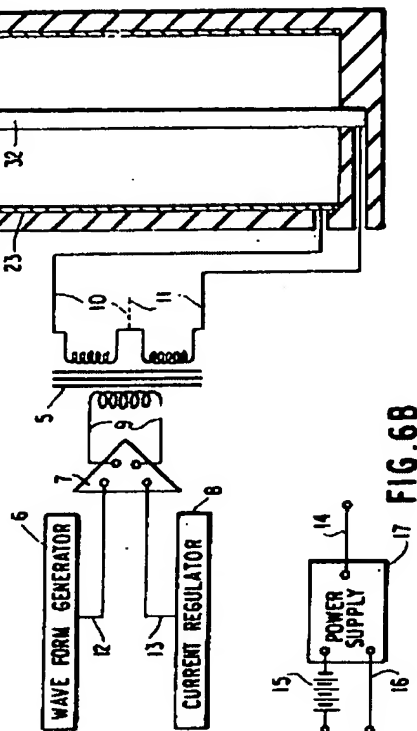


FIG. 6B

21. EAST - (Default EAST Workspace (Flat Panel LANDSCAPE).wsp:1)

EAST - Default EAST WorkSpace [List Panel LANDSCAPE] wsp(1)

Drafts
☐ Pending
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- L1: (14571) (205/50-333).CCLS.
- L2: (4611) waveform adj generator
- L3: (12) 11 and 12
- L4: (16883) (204/198-297.16).CCLS.
- L5: (15) 12 and 14
- L6: (11) 15 not 13
- L7: (187378) triangular or triangle
- L8: (25336) sawtooth or (saw adj tooth)
- L9: (207945) l7 or l8
- L10: (451256) wave or waves or waveform or waveforms
- L11: (16752) l9 near2 l10
- L12: (59) l1 and l1l

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L1 and L1L				

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Document ID	Pages	U	S	C	P	Kind Codes	Source
US 6500324 B1	10	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
US 6346182 B1	15	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
US 6334945 B1	11	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
US 6174425 B1	10	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
US 6171952 B1	9	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
US 6143158 A	27	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
US 6103087 A	29	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT

US-PAT-NO: 6143158

DOCUMENT-IDENTIFIER: US 6143158 A

TITLE: Method for producing an aluminum support for a lithographic printing plate

----- KWIC -----

Detailed Description Text - DETX (135):

As to AC power supply waveforms used in electrochemical surface roughening, a sine wave, a rectangular wave, a trapezoidal wave and a triangular wave can be used. A rectangular wave or a trapezoidal wave as shown in FIG. 9 is preferred, and a trapezoidal wave is particularly preferred.

Current US Original Classification - CCOR (1):
205/219

United States Patent

Nishino et al.

[19]

(11) Patent Number:

6,143,158

[45] Date of Patent:

Nov. 7, 2000

[54] METHOD FOR PRODUCING AN ALUMINUM SUPPORT FOR A LITHOGRAPHIC PRINTING PLATE

[75] Inventors: Aizawa Nishino; Yoshitaka Masuda; Aldo Uetani, all of Shizuoka, Japan

[73] Assignee: Fuji Photo Film Co., Ltd.,
Mitsumi-Ashigara, Japan

[21] Appl. No.: 09/063,727

[22] Filed: Apr. 24, 1998

[30] Foreign Application Priority Data

Apr. 25, 1997 [JP] Japan 9-109528
Jun. 23, 1997 [JP] Japan 9-166143

[51] Int. Cl. C25D 5/24; B23H 11/00; C25F 3/00

[52] U.S. Cl. 205/219; 205/658; 205/660; 205/662; 205/672; 205/674

[58] Field of Search 205/658, 659, 205/660, 661, 672, 674, 219, 220, 214, 212, 662

References Cited

U.S. PATENT DOCUMENTS

4,536,264 8/1985 Masuda et al.
4,561,944 12/1985 Sasaki et al.
4,902,389 2/1990 Nishino et al.
5,141,885 8/1992 Nishino et al.

FOREIGN PATENT DOCUMENTS

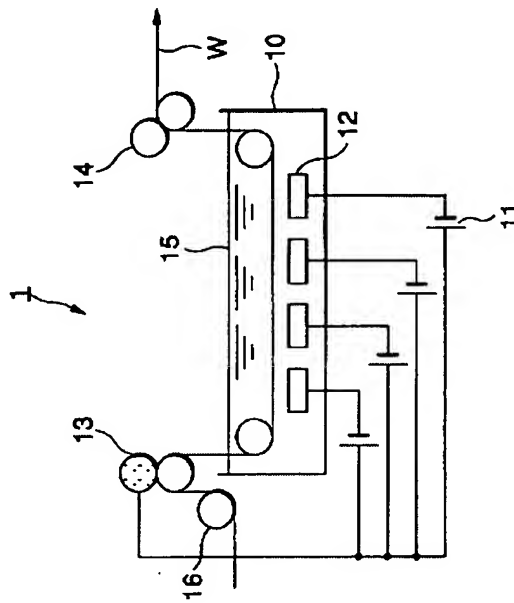
059179 5/1994 European Pat. Off.
52-5312323 3/1977 Japan
55-137893 10/1980 Japan
57-46436 10/1982 Japan
62-0176594 12/1987 Japan
62-176185 7/1988 Japan
1-03104694 9/1988 Japan
10183400 7/1990 Japan
04289700 3/1991 Japan
9-277735 10/1997 Japan

Primary Examiner—Donald R. Valentine
Attorney, Agent, or Firm—Burns, Doane, Swecker & Mathis, LLP

ABSTRACT

A method for producing an aluminum support for a lithographic printing plate comprising the steps of (a) electrolytic polishing an aluminum plate in an alkaline aqueous solution; and (b) electrochemically surface roughening the aluminum plate using direct or alternating current in an acidic aqueous solution in this order, and also a method for producing an aluminum support for a lithographic printing plate comprising an electrolytic polishing step of treating an aluminum plate used as an anode in an alkaline aqueous solution at a current density of 5 A/dm² to 200 A/dm² while allowing the alkaline aqueous solution to flow between the aluminum plate and an electrode at an average flow rate of 10 cm/second to 400 cm/second.

24 Claims, 8 Drawing Sheets



Document ID	Pages	U	S	C	P	Kind Codes	Source
US 5935408 A	7						USPAT
US 5865978 A	21						USPAT
US 5837121 A	7						USPAT
US 5832834 A	11						USPAT
US 5804400 A	16						USPAT
US 5788819 A	48						USPAT
US 5705230 A	9						USPAT

US-PAT-NO: 5705230

DOCUMENT-IDENTIFIER: US 5705230 A

TITLE: Method for filling small holes or recesses in the surface of substrates

----- KWIC -----

Detailed Description Text - DCTX (3):

In the step of deposition, a controlled varying voltage and/or an energy such as low-frequency, high-frequency or ultrasonic vibrations or a light beam is preferably applied to the substrate. The applicable varying voltage includes voltages of pulsed waveforms such as square wave, trapezoidal wave, triangular wave, sinusoidal wave and random wave. The voltages of such pulsed waveforms may have both positive and negative polarities or they may have only negative polarity. The repetitive voltage components may be zero at periodic times; alternatively, a d.c. component may be added to a periodic wave. The value of the voltage to be applied is preferably such that a maximum absolute value of current density on the surface of the substrate is in the range of from 10 sup.-3 to 1 A/cm.sup.2. The low-frequency, high-frequency or ultrasonic vibrations are preferably such that their frequency is in the range of from 45 Hz to 2.5 GHz.

Current US Cross Reference Classification - CCXR (1):
205/104Current US Cross Reference Classification - CCXR (2):
205/191Current US Cross Reference Classification - CCXR (3):
205/91

United States Patent

(19)

Matanabe et al.

US05/05230A

(11) Patent Number: 5,705,230

(45) Date of Patent: Jan. 6, 1998

[54] METHOD FOR FILLING SMALL HOLES OR COVERING SMALL RECESSES IN THE SURFACE OF SUBSTRATES

[75] Inventors: Taro Matanabe, Koganei, Japan;
N.Y.; Hirokazu Kawa, Tokyo, Japan;
Masahiro Miyata, Chiba-ken, Japan;
Yukio Ikeda, Tokyo, Japan; Manabu
Tajima, Kanagawa-ken, Japan;
Hirotaki Inoue, Kanagawa-ken, Japan;
Takayuki Ohtsuka, Kanagawa-ken,
Japan; Naoki Ogura, Tokyo, Japan

[73] Assignee: Ebara Corporation, Tokyo, Japan

[21] Appl. No.: 304,460

[22] Filed: Oct. 17, 1994

Related U.S. Application Data

[63] Continuation of Ser. No. 32,657, Mar. 17, 1993, abandoned.

[30] Foreign Application Priority Data

Mar. 17, 1992 [JP] Japan 4,091,778

[51] Int. Cl.⁶ B65D 1/18

[52] U.S. Cl. 427/438; 205/91; 205/104; 205/191

[58] Field of Search 205/91; 427/437; 438; 443.1; 595

[56] References Cited

U.S. PATENT DOCUMENTS

3,194,681 7/1965 Nickelson 427/601
4,002,778 1/1977 Bellis et al. 427/68
4,029,631 5/1977 Castilho 205/126
4,217,183 8/1980 Makher 205/92
4,239,789 12/1980 Hiron 427/555
4,251,327 2/1981 Gerson 205/66
4,349,383 9/1982 Kalyach 427/91

OTHER PUBLICATIONS

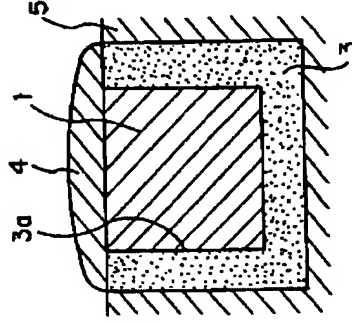
A.A. Wang, et al. "Local Mass Transfer by Free Convection with Simultaneous Heat Transfer," *Electrochimica Acta* V.18 pp.19 (Mar. 1973).
"Electrodeposition of Metals in Ultrasonic Fields," Sergei Mikhailovich Kozlov, Galina Yakovlevna Vydevleva, Consultants Bureau, New York (1966) pp. 41 and 44 month unavail.
Selective Electroless Plated Ni Contact to CMOS Junctions with CoSi₂, G. E. Georgiou, et al. *J. Electrochem. Soc.* V.138 No. 12, Dec. 1991.
Anodic Oxidation of Reductions in Electroless Plating, Izumi Ohta, et al. *J. Electrochem. Soc.*, vol. 132, No. 10, Oct. 1985.

Primary Examiner—John Nishling
Assistant Examiner—Eredeen Mee
Attorney Agent, or Firm—Oshim, Spivak, McOlland,
Matis & Neustadt, P.C.

[57] ABSTRACT

The improved method comprises contacting a substrate S at least once by a liquid containing the elements that compose a pure metal or an alloy with which the small holes or recesses S₀ in the substrate S are to be filled or covered, whereby the liquid wets the inner surfaces of said small holes or recesses S₀ while, at the same time, said pure metal or said alloy is deposited on the surface of said substrate S. The method is capable of filling small holes or covering small recesses in the surface of the substrate S with improved efficiency while, at the same time, it improves the heat resistance and materials robustness of the part that contains the formed filling or covering layer.

3 Claims, 4 Drawing Sheets



Application Number Informa.

Docset: JWC 204 DUE

EAST: JWC 204 DUE

EAST: JWC 204 DUE

EAST: JWC 204 DUE

EAST: JWC 204 DUE

Doc ID	Pages	U	S	C	P	Kind Codes	Sort
16 US 5832834 A	11						USPAT
17 US 5804400 A	16						USPAT
18 US 5788819 A	48						USPAT
19 US 5705230 A	9						USPAT
20 US 5662788 A	6						USPAT
21 US 5616229 A	8						USPAT
22 US 5437779 A	7						USPAT

US-PAT-NO: 5437779

DOCUMENT-IDENTIFIER: US 5437779 A

TITLE: Method of making a magnetic record medium

----- RWIC -----

Drawing Description Text - DRWX (2):

FIGS. 1(A) through 1(D) show examples of alternating waveform currents employed in the present invention, wherein FIG. 1(A) designates a sinusoidal waveform, FIG. 1(B), a rectangular waveform, FIG. 1(C), a trapezoidal waveform, and FIG. 1(D), a triangular waveform.

Detailed Description Text - DETX (4):

In this invention, the textured surface of the substrate is electrolyzed in an electrolyte of an acidic solution by applying an electric potential on the substrate. As an electrolyte, for instance, an aqueous solution of at least one selected from the group consisting of sulfuric acid, nitric acid, hydrochloric acid, chromic acid, phosphoric acid, oxalic acid, and acetic acid in a range of concentration of 0.5 through 40 weight %, preferably 1 through 30 weight %, and particularly phosphoric acid is preferable. As for the electrolytic conditions, it is preferable that the substrate is treated wherein an electric potential is applied on the substrate in the electrolyte, the solution temperature is in a range of 10.degree. through 70.degree. C., the current density is in a range of 0.1 through 30 mA/cm.sup.2, preferably 0.5 through 45 mA/cm.sup.2, more preferably 1.0 through 20 mA/cm.sup.2, the electrolytic time is in a range of 1 through 400 seconds, preferably 2 through 200 seconds, and the quantity of electricity (a product of current density by electrolytic time) is in a range of 10 through 1000 mA.multidot.second/cm.sup.2, preferably 50 through 600 mA.multidot.second/cm.sup.2. The electric potential applied in the electrolysis reaction is a direct current or an alternating waveform current wherein the polarities are alternately reversed, and especially the alternating waveform current is preferable. When a direct current potential is employed, it is preferable to perform the treatment with current density in a range of 1.0 through 25 mA/cm.sup.2. The alternating waveform current is provided by alternately reversing (converting) the positive and negative polarities, that is, the polarities of anode and cathode, which is, for instance, a single phase alternating current of a sinusoidal wave, a three-phase alternating current of a sinusoidal wave, a rectangular wave, a triangular wave, a trapezoidal wave or the like. The frequency of the alternating waveform current is not smaller than 0.1 and smaller than 300 Hz, preferably in a range of 0.1 through 300 Hz, more preferably in a range of 0.5 through 200 Hz. Further, it is preferable to select a ratio (Q.sub.a / Q.sub.c) of the quantity of electricity in anode time (Q.sub.a) over the quantity of electricity in cathode time (Q.sub.c) in case of employing the alternating waveform current, is in a range of 0 through 2.0, preferably 0.8 through 1.5, more preferably 0.9 through 1.1.

Current US Original Classification - CCOR (1):
205/106

United States Patent (19)

Shige et al.

US0543777A

(11) Patent Number: 5,437,779

(43) Date of Patent: Aug. 1, 1995

[54] METHOD OF MAKING A MAGNETIC RECORD MEDIUM

[75] Inventors: Tomoo Shige, Yasushi Makabe, Masataka Yokoyama, all of Kurashiki, Japan

[73] Assignee: Mitsubishi Chemical Corporation, Tokyo, Japan

[21] Appl. No.: 163,551

[22] Filed: Dec. 9, 1993

[30] Foreign Application Priority Data

Dec. 11, 1992 [JP] Japan 4-31665

[51] Int. Cl.⁶ C25D 5/24

[52] U.S. Cl. 205/106; 204/192.2;

205/701; 205/206; 205/214; 427/129

[58] Field of Search 205/206, 214, 219, 198;

205/199, 200, 201, 106, 107; 204/192.2;

427/129

[56] References Cited

U.S. PATENT DOCUMENTS

5,057,200 10/1991 Lal et al. 204/192.15

5,223,304 6/1993 Yasuda et al. 427/129

FOREIGN PATENT DOCUMENTS

118493 7/1989 Japan

OTHER PUBLICATIONS

Lovenheim, Anodizing Aluminum, *Electroplating*, pp. 451-461 (1978) [no month].

Graham, Convection Coating Process, *Electroplating Engineering Handbook* 3rd edition, pp. 456-464 (1971) [no month].

Primary Examiner—John Nibbling

Assistant Examiner—Edna Wong

Attorney, Agent, or Firm—Obion, Spivak, McClelland,

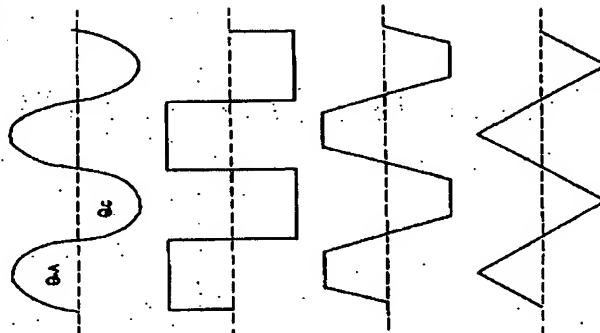
Mak & Neustadt

[37]

ABSTRACT

A method of making a magnetic record medium comprising the steps of: texturing a surface of a substrate by a first surface treatment; electrolyzing the surface of the textured substrate in an electrolyte of an acidic solution by applying an electric potential on the nonmagnetic substrate by a second surface treatment; and forming an undercoating layer and a magnetic layer on the surface of the electrolyzed substrate.

17 Claims, 1 Drawing Sheet



Document ID	Pages	U	S	C	P	Kind Codes	SQL
18 US 5789819 A	48	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
19 US 5703230 A	9	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
20 US 5662788 A	6	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
21 US 5616229 A	8	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
22 US 5437779 A	7	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
23 US 5384215 A	15	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
24 US 5364522 A	8	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT

US-PAT-NO: 5364522

DOCUMENT-IDENTIFIER: US 5364522 A

TITLE:
Boride, carbide, nitride, oxynitride, and silicide
infiltrated electrochemical ceramic films and coatings
and the method of forming such

----- KWIC -----

Detailed Description Text - DCTX (8):

A substrate subject to anodic coating is direct current positively polarized. A substrate subject to cathodic coating is direct current negatively polarized. An external voltage is connected across the two electrodes, a DC, or a pulsed DC, or a sine wave DC, or a sawtooth DC, or a triangular DC, or a stepped DC, and or a mixture thereof is passed through the electrodes and electrolytes.

Detailed Description Text - DCTX (9):

This invention relates that the preferred electric potentials or current waveforms consists of a pure DC, a pulsed DC, a sine wave DC, a sawtooth DC, a triangular DC, a stepped DC, a sine wave AC, and a mixture thereof.

Detailed Description Text - DCTX (11):

When a pulsed DC voltage, or a sine wave DC, or a sawtooth DC, or a triangular DC, or a stepped DC is applied, different ions will be coated at different potentials to form a layered ceramic precursor coating. A ceramic precursor composition with layered, laminar ultrastructures including superlattices are obtained by the modulating of the applied voltage or current. A multilayered, or laminar ultrastructures including a superlattice precursor coating can be obtained by the modulating of the applied voltage or current densities at the proper waveform or pulse frequency. An amplitude-modulated voltage or current density provides a finely controlled layered ceramic precursor composition. The invention also relates to the discovery that following an infiltration the multilayered and superlattice ceramic precursor coatings are infiltrated to multilayered and superlattice ceramic coatings having boride, carbide, nitride, oxynitride and silicide infiltrated concentration gradients with the maximum at surface and minimum in bulk of the parent ceramic coatings.

Claims Text - CLTX (10):

10. A method as claimed in claim 7 wherein said amplitude-modulated electric current is an electric current with a constant or time-varied waveform selected from the group consisting of a single pulse, a multiple pulse, a sine wave, a sawtooth, a triangular, a stepped shape, a convolution of different geometric shapes, and a mixture thereof.

Claims Text - CLTX (20):

20. A method as claimed in claim 16 wherein said amplitude-modulated electric current is an electric current with a constant or time-varied waveform selected from the group consisting of a single pulse, a multiple

United States Patent [19]

Wang

[11] Patent Number: 5,364,522

[45] Date of Patent: Nov. 15, 1994

[54] BORIDE, CARBIDE, NITRIDE,
OXYNITRIDE, AND SILICIDE
INFILTRATED ELECTROCHEMICAL
CERAMIC FILMS AND COATINGS AND
THE METHOD OF FORMING SUCH

[76] Inventor: Liang Wang, 5129 Maddox Rd.,
Tallahassee, Fla. 32303

[21] Appl. No.: 33/434

[22] Filed: Mar. 22, 1993

[31] Int. Cl.: C25D 1/00, C25D 3/02

[32] U.S. Cl.: 205/224, 205/118, 205/229, 208/162, 208/174,

208/316, 428/446, 428/689, 428/688, 428/693,

428/704

[58] Field of Search: 205/99, 106, 108, 224,

205/229, 118, 174, 316, 162, 428/446, 698, 702

[56] References Cited

U.S. PATENT DOCUMENTS

4,882,014 2/1988 Coyle 204/1.5

FOREIGN PATENT DOCUMENTS

0047115 12/1981 European Pat. Off. 204/316

OTHER PUBLICATIONS

Chemical Abstracts, vol. 34, p. 187, Abs. #124792p.

Chemical Abstracts, vol. 64, p. 10898, Abs. #10898A.

Chemical Abstracts, vol. 103, p. 292, Abs. #119573c.

Chemical Abstracts, vol. 89, p. 538, Abs. #137638c.
Chemical Abstracts, vol. 93, p. 256, Abs. #119055g.
Science, 1992, 258, 1918-1921.
J. Electrochem. Soc., 1991, 138, 1038-1040.

Electrochim. Acta 1992, 37, 2421-2424.

Nature, 1992, 357, 395-397.

J. Electrochem. Soc., 1991, 138, 1643-1645.

J. Electrochem. Soc., 1992, 139, 67-69.

J. Electrochem. Soc., 1990, 127, 2033-2037.

Chem. Abstracts, vol. 57-Ceramics p. 265; Abst.

119066g.

Primary Examiner—Kathryn Gorgas

[57] ABSTRACT

Ceramic films and coatings, single or multi-layered, including superlattice, infiltrated with boride, carbide, nitride oxynitride and silicide were formed by methods which comprises of an electrochemical coating of a ceramic precursor by a constant or an amplitude-modulated electric current with a DC component in a medium containing at least one of the ionic species for the composition of the ceramic precursor, following single or multiple infiltration in a medium containing at least one of the compounds selected from a B-containing compound, a C-containing compound, a N-containing compound, a Si-containing compound, and a mixture thereof, by heating means selected from radio-frequency, microwave, thermal, flame, plasma, laser, and a mixture thereof.

24 Claims, No Drawings

Document ID	Pages	U	S	C	P	Kind	Code	Sub
23 US 5384215 A	15	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT	
24 US 5364522 A	9	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT	
25 US 5320719 A	10	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT	
26 US 5268235 A	10	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT	
27 US 5171416 A	8	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT	
28 US 5158653 A	9	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT	
29 US 5147515 A	8	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT	

US-PAT-NO: 5147515

DOCUMENT-IDENTIFIER: US 5147515 A

TITLE: Method for forming ceramic films by anode-spark discharge

----- KWIC -----

Brief Summary Text - B9TX (31):

The output from a power supply may be a direct current having any wave form, but preferably those having pulse shape (rectangular wave form), saw-tooth wave form or DC half-wave form.

Current US Cross Reference Classification - CCXR (1):
205/320Current US Cross Reference Classification - CCXR (2):
205/321Current US Cross Reference Classification - CCXR (3):
205/322Current US Cross Reference Classification - CCXR (4):
205/323

United States Patent (19)

Hanagata et al.

US0514751A

(11) Patent Number: 5,147,515

(43) Date of Patent: Sep. 15, 1992

1,964,616 6/1976 Miyawaka et al. 203/723

FOREIGN PATENT DOCUMENTS

151330 10/1981 Fed. Rep. of Germany
15603 7/1982 Fed. Rep. of Germany

Primary Examiner—John Niebling
Assistant Examiner—Brian M. Bolam
Attorney Agent, or Firm—Obdon, Spivak, McClelland,
Moser & Neustadt

[57]

ABSTRACT

A method for forming a ceramic film on the surface of a substrate comprises performing spark discharge in an electrolytic bath, wherein the electrolytic bath comprises an aqueous solution of a water-soluble or colloidal silicate and/or an oxyacid salt to which ceramics fine particles and/or specific fine particles are dispersed and the spark discharge is carried out in the electrolytic bath while ensuring the suspended state of the ceramics particles and/or the specific fine particles in the electrolytic bath. The method makes it possible to effectively form, on the surface of a metal substrate, ceramics films having a variety of color tones as well as excellent insulating properties and hardness. Moreover, it further makes it possible to effectively form a composite ceramics film having excellent wear resistance on the surface of a metal substrate.

13 Claims, No Drawings

[54] BY ANODE-SPARK DISCHARGE

[75] Inventors: Haruo Hanagata, Ebinai, Tanaka
Sumaki, Kazuo Yaezaki, both of
Kanagawa; Hidekazu Iguchi, Tokyo,
all of Japan

[73] Assignee: Dipsol Chemicals Co., Ltd., Tokyo,
Japan

[21] Appl. No.: 573,703

[22] Filed: Aug. 28, 1990

[20] Foreign Application Priority Data

Sep. 4, 1989 [JP] Japan 1-228519
Mar. 6, 1990 [JP] Japan 2-94817

[31] Int. Cl. H05F 3/04

[32] U.S. Cl. 204/164; 205/320; 205/321; 205/322; 427/37

[38] Field of Search 204/56.1, 58, 58.4, 204/164; 427/37; 106/628, 633, 637; 264/722; 205/311, 322, 323, 320

[56] References Cited

U.S. PATENT DOCUMENTS

3,812,021 5/1974 Craig et al. 204/58
3,812,022 5/1974 Rogers et al. 204/58
3,822,253 6/1974 Hindcovity et al. 204/38.4
3,996,080 3/1976 Hindcovity et al. 204/38.4

Application Number Entered

EAST BROWER 11/21/03

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Document ID	Pages	U	S	C	P	Kind	Codes	Source
31 US 5141602 A	27	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>			USPAT
32 US 5124022 A	9	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>			USPAT
33 US 5045157 A	5	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>			USPAT
34 US 5032237 A	12	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>			USPAT
35 US 5030331 A	5	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>			USPAT
36 US 4976827 A	6	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>			USPAT
37 US 4923574 A	20	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>			USPAT

US-PAT-NO: 4923574

DOCUMENT-IDENTIFIER: US 4923574 A

TITLE: Method for making a record member with a metallic antifriction overcoat

----- KWIC -----

Brief Summary Text - BPTX (19):

If desired, the plating current density (or cathode potential) used to produce the multilayered structure may be selected to have a stepped, triangular, or sinusoidal waveform which is a periodic function of time. Once the plating bath is selected the composition and thickness of each layer is selected independently by controlling the current density (or cathode potential), as a function of time.

Drawing Description Text - DPTX (8):

FIG. 7 shows a triangular or swept waveform for applied current density as a function of time.

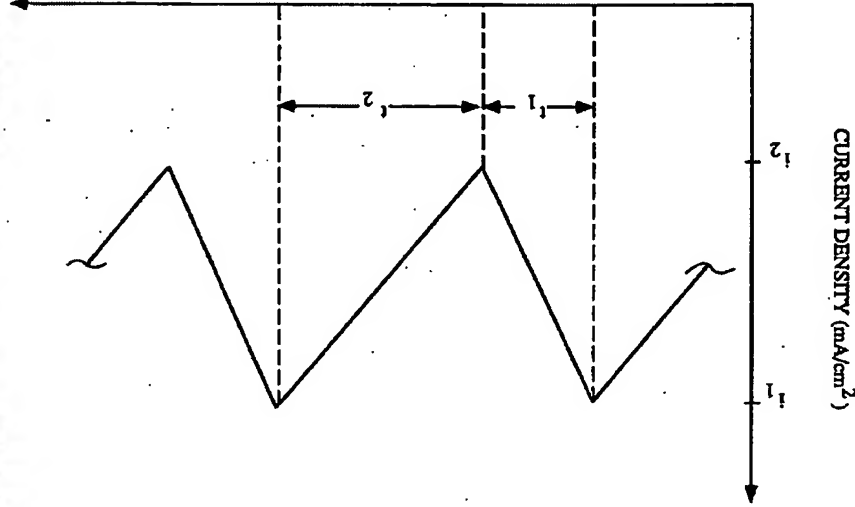
Detailed Description Text - DETX (43):

It should be noted that the duration of the high or low values of current density as illustrated by the waveform shown in FIG. 5 can be varied and controlled by the function generator to achieve desired thickness of the layers Li, . . . Ln. The thickness of each layer is directly related to the amount of electric charge utilized during its electroplating. Thus, for a given current density, the thickness of a layer is controlled by the time the current is applied to the electrolytic cell. The composition of the plated alloy can be varied and controlled by changing the current density (or cathode potential) to a value which gives the desired composition. FIG. 7 provides another example of a graph of a current density versus time which may be used to generate another layered structure. A similar waveform may be applied to the cathode potential. The result of the use of this triangular or swept waveform is a triangular or graded variation in the composition of the alloy layers plated.

Detailed Description Text - DETX (44):

FIGS. 5 and 7 are merely examples of the many waveforms which may be employed in order to form a layered structure. Other alternative embodiments of the present invention include electroplating more than two layers per cycle. This is accomplished by creating a series of different current densities or cathode potentials before repeating the cycle. Thus, it can be seen that the method of this invention permits the design of a resulting plated structure by variation of the magnitude of the current or cathode potential applied and the duration that a given current density or cathode potential is applied. In particular, the waveform shown in FIG. 8 may be used to produce four layers per cycle: a first layer of graded composition during time period t.sub.1; a second layer of constant composition during time period t.sub.2; a third layer of graded composition during time period t.sub.3; and a fourth layer of constant composition during time period t.sub.4. Similarly, other combinations of stepped, triangular, and sine waveforms may also be utilized.

FIG. 7



[illegible]

Document ID	V	Pages	U	S	C	P	Kind	Code	Source
950	US 4341621 A	5							USPAT
951	US 4341617 A	6							USPAT
952	US 4340456 A	5							USPAT
953	US 4340276 A	13							USPAT
954	US 4339310 A	5							USPAT
955	US 4338187 A	12							USPAT
956	US 4338176 A	5							USPAT

US-PAT-NO: 4338176

DOCUMENT-IDENTIFIER: US 4338176 A

TITLE: System for generating and autocontrolling the voltage or current wave form applicable to processes for the electrolytic coloring of anodized aluminium

----- RWIC -----

Assistant Examiner - XA (1):
Leader: William

United States Patent

Garcia Pelaez

[19]

[54] SYSTEM FOR GENERATING AND AUTOCONTROLLING THE VOLTAGE OR CURRENT WAVE FORM APPLICABLE TO PROCESSES FOR THE ELECTROLYTIC COLORING OF ANODIZED ALUMINIUM

[75] Inventor: Jose Garcia Pelaez, Alicante, Spain

[73] Assignee: Empresa Nacional del Aluminio, S.A., (ENXASA), Madrid, Spain

[21] Appl. No.: 83,943

[22] Filed: Oct. 11, 1979

[30] Foreign Application Priority Data

Oct. 31, 1978 [ES] Spain 474,736

[31] Int. Cl. C10D 11/24; C05F 1/44

[32] U.S. Cl. 204/228; 204/DIG. 9;

[33] Field of Search 323/281; 330/265; 363/97;

204/DIG. 9; 204, 205, 211, 218, 223; 363/97;

330/259, 265, 271, 293, 297; 323/273, 281

[36] References Cited

U.S. PATENT DOCUMENTS

3,450,025 12/1970 Sodabity

3,475,496 4/1973 Carman

3,815,014 9/1976 Newman et al.

4,011,132 3/1977 Rodriguez-Martin

4,041,367 8/1977 Gold et al.

OTHER PUBLICATIONS

John D. Lamb, Handbook of Modern Solid-State Amplifiers, Prentice-Hall, Inc., Englewood Cliffs, New Jersey, 1974, pp. 334-338.

Primary Examiner—Delbert E. Gantz

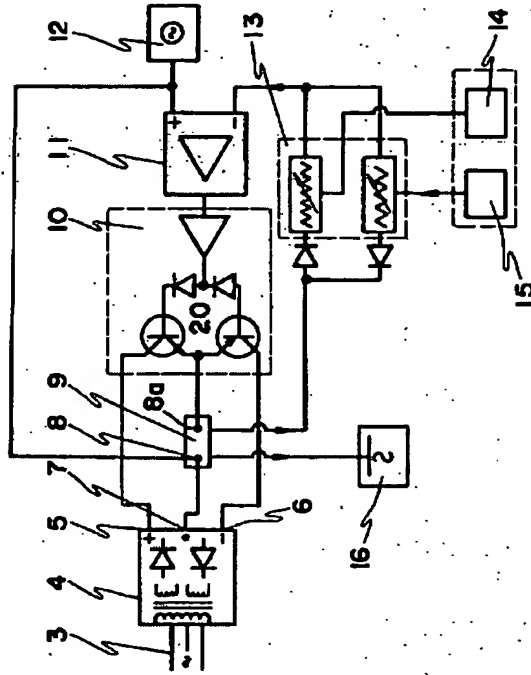
Assistant Examiner—William Leader

Attorney, Agent, or Firm—Wendroth, Lind & Ponack

[57] ABSTRACT

A system for generating and autocontrolling the voltage or current wave form in a process for the electrolytic coloring of anodized aluminium includes feeding power from a source of symmetrical direct current, with a neutral connection directly coupled to a load, while the positive and negative voltages supplied by the source pass through a power control stage which is controlled by a bipolar operational amplifier. The bipolar operational amplifier has two signal inputs, a positive or non-inverting input which is connected to a signal generator, and a negative or inverting input having a signal which corresponds to the signal which actually exists on the electrodes of the electrolytic bath. This signal is processed in a half-wave outer controller which is controlled by a programming system.

7 Claims, 3 Drawing Figures



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Drafts

☐ Pending ☒ Approved

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Urbair, Oscar
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916: (178481) 14 04 15

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1. *Introduction*
 2. *Background*
 3. *Methodology*
 4. *Results*
 5. *Discussion*
 6. *Conclusion*
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- Page No. 1
- Date: 10/10/2019
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2. The second part of the document is a table with the following columns:

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Figure 1. The effect of the concentration of the *Agrobacterium* suspension on the transformation efficiency of *Agrobacterium* strains. The *Agrobacterium* strains were grown in YEA medium for 24 h at 28 °C. The cell concentration was adjusted to 10⁸ cells/ml. The cells were then mixed with the plant tissue and the transformation efficiency was determined. The results are shown as the mean ± SD of three independent experiments. The asterisk indicates a significant difference (p < 0.05) between the control and the treated groups.

The following table shows the results of the regression analysis for the dependent variable *Perceived Stress*. The independent variables are *Age*, *Gender*, *Marital Status*, *Income*, *Education*, *Health Status*, *Work Status*, *Family Size*, *Religious Beliefs*, and *Social Support*. The table includes the coefficient estimates, standard errors, t-statistics, and p-values for each variable.

Variable	Coefficient	Standard Error	t-statistic	p-value
Age	0.02	0.01	1.50	0.14
Gender	-0.15	0.08	-1.88	0.07
Marital Status	0.10	0.05	2.00	0.05
Income	-0.05	0.02	-2.50	0.02
Education	0.03	0.01	3.00	0.00
Health Status	0.18	0.03	6.00	0.00
Work Status	-0.12	0.04	-3.00	0.00
Family Size	0.08	0.02	4.00	0.00
Religious Beliefs	-0.05	0.01	-5.00	0.00
Social Support	-0.10	0.02	-5.00	0.00

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Document ID	V	Pages	U	S	C	P	Kind	Codes	Source
1	US	H000872	H	8					USPAT
2	US	654979	B2	18					USPAT
3	US	6537433	B1	18					USPAT
4	US	6506439	B1	8					USPAT
5	US	6503579	B1	19					USPAT
6	US	6475351	B2	21					USPAT
7	US	6451181	B1	15					USPAT

US-PAT-NO: 6451181

DOCUMENT-IDENTIFIER: US 6451181 B1

TITLE: Method of forming a semiconductor device barrier layer

----- KWIC -----

Detailed Description Text - DCTX (56):

FIG. 14 illustrates yet a third possible waveform 604 which may be used to form the barrier layer 220, of FIG. 10. Waveform 604 shows that pulsed power (either periodic or nonperiodic) is applied to the coil 52. When using a pulsed coil power waveform as in FIG. 14, alternating layers or portions of less tensile and more tensile tantalum can be incrementally deposited on the wafer 22 to form the barrier layer 220, of FIG. 10. Therefore, it has been determined that selectively powering on and off the coil at least once during the deposition process can be used to tune the stress of the barrier layer to accommodate a plurality of differing constraints or conditions. In addition, although FIG. 14 shows primarily step coverage wave forms, the waveforms that can be used on the coil, target, and/or wafer need not be step-function curves over time. For example, it is possible to use triangle-shaped (sawtooth) waveforms, sinusoidal waveforms, logarithmic power curves, exponential power curves, combination thereof, or any other types of analog, continuous, or quantized wave forms to produce different types of stress characteristics of the tantalum (or refractory metal based) barrier layer 220 of FIG. 10. Alternatively, this processing methodology can be used with a variety of other conductive films, such as metals, refractive metals, and refractive metal nitrides which may be prone to stress related problems. In addition, while less tensile and more tensile are used to described the relative stress of materials throughout this specification, those skilled in the art will appreciate that the terms less tensile and more compressive can be used interchangeably.

Current US Class - CLASS (1):
204

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United States Patent

Denning et al.

(10) Patent No.: US 6,451,181 B1

(45) Date of Patent: Sep. 17, 2002

(34) METHOD OF FORMING A SEMICONDUCTOR DEVICE BARRIER LAYER

(75) Inventors: Dean J. Denning, Del Valle, Sam S. Garcia, Austin; Bradley P. Smith, Austin; Daniel J. Loop, Austin; Gregory Norman Hamilton, Pflugerville, Md.; Habel Islam; Brian G. Anthony, both of Austin, all of TX (US)

FOREIGN PATENT DOCUMENTS

EP 0818358 1/1998
EP 0943545 6/1998
FR 2436623 4/1990
JP 59288071 11/1984
JP 6390404 12/1988
JP 10031158 12/1998
WO 98/24377 12/1998

OTHER PUBLICATIONS

EPO 00104085 Search Report, 2 pgs.

* cited by examiner

Primary Examiner—Rodney G. McDonald

(74) Attorneys, Agent, or Firm—Robert A. Rodriguez; Keith E. Witak

(57) ABSTRACT

A method for forming an improved copper inlay interconnect (FIG. 11) begins by performing an RF pre-clean operation (408) on the inlay structure in a chamber (10). The RF pre-clean rounds corners (210a and 206a) of the structure to reduce voiding and improve step coverage while not significantly removing copper atoms from the underlying exposed copper interconnect surfaces (202a). A tantalum barrier (220) is then deposited where one portion of the tantalum barrier is more tensile than another portion of the tantalum barrier. After formation of the barrier layer (220), a copper seed layer (222) is formed over a top of the barrier layer. The copper layer is formed while clamping the wafer with an improved clamp (85) which reduces copper peeling and contamination at wafer edges. Copper decoupling and chemical mechanical polishing (CMP) processes are then used to complete the copper interconnect structure.

6 Claims, 6 Drawing Sheets

(21) Appl. No.: 09/261,879

(22) Filed: Mar. 2, 1999

(31) Int. Cl.⁷ C23C 14/34

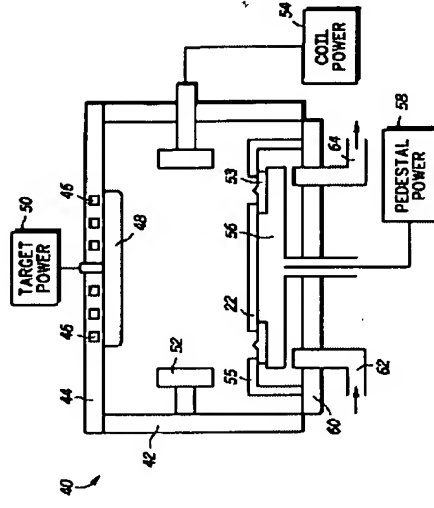
(52) U.S. Cl. 204/192.12; 204/192.15; 204/192.17; 204/192.3; 204/298.06; 438/582; 438/652; 438/653; 438/656; 438/685; 438/698

(58) Field of Search 204/192.12, 192.15; 204/192.17, 192.3; 204/298.06; 438/582; 438/652, 653, 656, 685

(56) References Cited

U.S. PATENT DOCUMENTS

4,999,096 A * 3/1991 Nihai et al. 204/192.3
5,175,608 A 12/1992 Nihai et al.
5,707,498 A 1/1998 Nga 204/192.12
6,080,285 A * 6/2000 Lin et al. 204/192.12
6,139,699 A * 10/2000 Chang et al. 204/192.15



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6 US 6332937 B1	15	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
7 US 6290834 B1	5	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT

Brief Summary Text - BSRX (8):

A desirable improved process would be one which has little or no ceramic re-melt or liquid flow on application of the laser to cut the ink-well patterns. Additionally, a desirable process would leave holes or cells having sharply defined patterns, having walls which are smooth and of the same texture as the surrounding area, to facilitate ink (and other material) to be transferred) removal and cleanup as well as more precise patterns. Easier cleanup increases productivity and minimizes the chances of damage to the roll surface. And, a desirable process would be one which does not demonstrate a significant shortcoming of the thermal spray processes--the sometimes inadequate adherence of the coating to the roll substrate. This is an inherent difficulty with the thermal spray processes particularly for substrates, such as aluminum, having coefficients of thermal expansion considerably different from the ceramic coating.

Brief Summary Text - BSRX (9):

Further, it would be desirable to have a process wherein the laser-produced cell patterns are imparted to the roll surface prior to application of the ceramic coating rather than after, since application of the laser after coating incorporates all the above possible defects and shortcomings, and results in vertical surfaces in the cells which are different in composition from the horizontal surfaces. Coating after engraving is not feasible with sprayed ceramics.

Brief Summary Text - BSRX (16):

In another version of my invention, a hard wear resistant ceramic coating is formed on an incipient process roll having a blank metal surface by immersing it in an electrolytic bath comprising (deionized) water, an electrolytic agent comprising an alkali metal salt or hydroxide (preferably potassium hydroxide) at a concentration of 0.5-7 grams per liter, and, as a passivating agent, a colloidal suspension of sodium silicate in the form Na₂SiO₃·2 H₂O, sub. 2 (56ft:2.55 by weight) at a concentration of 2.0-9.5 grams per liter while conducting through the bath a modified shaped-wave alternating electric current from a source of at least 250-800 volts through the surface of the incipient printing (process) roll. The modified shaped-wave electric current rises from zero to its maximum height and falls to below 40% of its maximum height within less than a quarter of a full alternating cycle, thereby causing dielectric breakdown and the formation of a compact ceramic film on the roll surface. I then remove the roll from the bath, grind or polish the formed ceramic coating to a suitably smooth finish, and engrave or emboss its surface, preferably by laser, to impose a three-dimensional pattern on the ceramic coating surface of the roll.

Detailed Description Text - DPTX (2):

The electrolytic treatment of the incipient liquid transfer roll will generally take about 30 to about 240 minutes to form a ceramic coating of 25 to 300 microns (0.001 to 0.012 inch) thick. A preferred thickness for the coating is 100 to 200 microns (0.004 to 0.012 inch) thick. Where the roll is aluminum, during the process cycle the substrate temperature is preferably maintained at less than 60 degrees C. (140 degrees F.). The incipient blank liquid transfer roll will preferably have an aluminum surface, but it may be made of aluminum, magnesium, titanium, zirconium, beryllium, hafnium or alloys thereof.

Detailed Description Text - DPTX (7):

200-810,117 20-22 hertz
WML 5050

United States Patent

Pearsall

(10) Patent No.: US 6,290,834 B1
(45) Date of Patent: Sep. 18, 2001

(34) CERAMIC COATED LIQUID TRANSFER ROLLS AND METHODS OF MAKING THEM

(75) Inventor: Thomas J. Pearsall, Summerfield, FL (US)

(73) Assignee: Ceramic Coatings Technologies, Inc., Palm City, FL (US)

(*) Notice: Subject to any disclaimer, the term of this patent is extended or adjusted under 35 U.S.C. 154(b) by 0 days.

(21) Appl. No.: 09/548,095

(22) Filed: Apr. 12, 2000

(31) Int. Cl.⁷ C23D 5/34

(52) U.S. Cl. 205/208; 205/120; 205/220

(58) Field of Search 205/220, 102, 205/205

(36) References Cited

U.S. PATENT DOCUMENTS

3,832,293 8/1974 Hudovsky et al. 204/56 R
3,834,999 9/1974 Hudovsky et al. 204/56 R
3,891,516 6/1975 Chu 204/33
3,956,080 3/1976 Hudovsky et al. 204/56 R
4,627,026 4/1978 Hudovsky 204/56 R
4,184,928 1/1980 Kozak 204/33 R
4,592,938 6/1980 Kozak 204/33 R
4,659,440 4/1987 Hudovsky 204/56 R

Primary Examiner—Kathryn Gogos
Assistant Examiner—Thomas H. Parsons
(74) Attorney, Agent, or Firm—William L. Krayer

(57) ABSTRACT

Liquid transfer rolls such as printing rolls are made by imposing a hard ceramic coating on an incipient liquid transfer roll in an electrolytic bath subjected to a modified shaped wave alternating current, which causes dielectric breakdown and the formation of a hard ceramic coating on the roll. The roll is laser engraved to form liquid carrying reservoirs or cells on the surface of the roll, either before or after the ceramic coating is built on the roll.

19 Claims, No Drawings

Doc. ID	Doc. No.	Doc. Title	Doc. Type	Doc. Status	Doc. Date	Doc. Author	Doc. Editor	Doc. Reviewer	Doc. Approver	Doc. Comments
5	US 6475644 B1	26	USPAT							
6	US 6332937 B1	15	USPAT							
7	US 6290834 B1	5	USPAT							
8	US 6261422 B1	9	USPAT							
9	US 6254759 B1	13	USPAT							
10	US 6248227 B1	8	USPAT							
11	US 6197178 B1	10	USPAT							

US-PAT-NO: 6197178

DOCUMENT-IDENTIFIER: US 6197178 B1

TITLE: Method for forming ceramic coatings by micro-arc oxidation of reactive metals

----- RWIC -----

Brief Summary Text - B8TX (5):

The practice of coating a metal substrate with a thin layer of a ceramic material has been used commercially for many years. One purpose of providing a ceramic coating of a metal is to improve the wear resistance of the metal from abrasion and another purpose is to protect the surface of the metal from thermal degradation, oxidation, or corrosion. In particular, research and development activity has been carried out throughout the world to provide superior surface properties to metals such as aluminum and aluminum alloys. Aluminum and aluminum alloys are extremely desirable metals for manufacturing machinery components and the like because they are relatively inexpensive and have relatively low densities. Aluminum and aluminum alloys, however, have the drawbacks of being relatively soft and do not resist wear and abrasion very well. In addition, aluminum is chemically active so that it tends to react with chemicals and even moisture in the air, thereby corroding.

Brief Summary Text - B8TX (6):

A known method of improving the surface of a substrate of aluminum or an alloy of aluminum is to apply a ceramic coating to the substrate by spraying the ceramic coating onto the substrate. Typically, the process of "flame spraying" includes a wire-type flame sprayer. The protective coatings applied in this manner are limited to those materials which can be formed into a wire or rod.

Brief Summary Text - B8TX (9):

Ceramic coatings used in the prior art are generally inherently porous and ordinarily do not provide much oxidation or corrosion protection to the base material. Thus, undercoats made from oxidation-resistant materials, or alloys are used between the base material and the ceramic coating if the substrate material is not corrosion resistant.

Brief Summary Text - B8TX (11):

Typically, one class of ceramic coatings has high thermal resistance and a low wear resistance, while another class of ceramic coatings has a high wear resistance and has a low thermal resistance. The general reason for this relationship is that ceramic coatings which have a high thermal resistance typically are more porous and have a higher void content thereby providing a good thermal barrier but also being less resistant to abrasion. A ceramic coating having a high abrasion resistance has a low void content, thus reducing damage to abrasion. Furthermore, in the prior art, only one specimen is connected to one electrode and the other electrode is connected to the electrolyte tank. Primarily, the power source was single phase AC and DC power.

see Fig 2B 10/018709 v. 10/018709

United States Patent

Patel et al.

(10) Patent No.: **US 6,197,178 B1**
(45) Date of Patent: **Mar. 6, 2001****METHOD FOR FORMING CERAMIC COATINGS BY MICRO-ARC OXIDATION OF REACTIVE METALS**

Inventors: Jerry L. Patel, Peabody; Nanaaji Saha, Cambridge, both of MA (US)

Assignee: Microplasma Corporation

Notice: Subject to any disclaimer, the term of this patent is extended or adjusted under 35 U.S.C. 154(b) by 0 days.

Appl. No.: 09/285,604

Filed: Apr. 2, 1999

Int. Cl.⁷ C25D 11/02; C25D 21/12
U.S. Cl. 205/81; 204/230.2; 205/96;
205/107; 205/137; 205/145; 205/151; 205/322;
205/324; 205/325; 205/326Field of Search 205/81, 82, 83,
205/96, 107, 137, 145, 320, 321, 322, 324,
325, 326, 328; 204/229.8, 230.2

References Cited

U.S. PATENT DOCUMENTS

3,611,654 • 1/1968 Duprez et al. 205/528
3,531,593 • 9/1970 Schneider 204/225
3,624,159 7/1974 Wehman 205/108
3,662,892 1/1975 Lautenschlager et al. 205/50
3,900,373 • 8/1975 Rajan, Jr. 205/337
3,956,080 5/1976 Hradcovsky et al. 205/316
4,149,912 4/1979 Craighead et al. 148/285
4,659,440 4/1987 Hradcovsky et al. 205/106
4,789,441 12/1988 Foster et al. 205/50
5,064,788 11/1991 Newkirk et al. 501/92
5,158,663 10/1992 Yablon 205/50
5,275,713 • 1/1994 Hradcovsky 205/106
5,385,662 1/1995 Kure et al. 205/316
5,427,678 6/1995 Masahiro et al. 205/322
5,616,229 4/1997 Samsonov et al. 205/107
5,700,366 12/1997 Seblanc et al. 205/87
5,720,866 2/1998 Ershine et al. 205/83
5,766,489 6/1998 Weinert et al. 2107/48

OTHER PUBLICATIONS

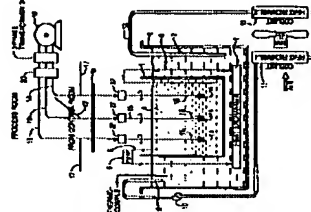
V. N. Malyshev et al., 'Features of the Structure and Properties of Coatings Applied by the Method of Microarc Oxidation', Khimicheskoe i Nefyayno Mashinostroenie, No. 1, pp. 26-27, Jan. 1984.
A. P. Efremov et al., 'Special Features of Formation of the Oxide Layer on Aluminum in Microarc Oxidation', Fiziko-Khimicheskaya Mekhanika Miroslav, vol. 25, No. 3, pp. 46-49, May-Jun. 1989.
P. S. Gerdzhanov et al., 'Kinetics of Formation of Microarc Oxidation Coatings on Aluminum Alloys', Zashchita Metallov, vol. 26, No. 3, pp. 467-470, May-Jun. 1990.
V. N. Kuskov et al., 'Special Features of Growth of the Coating in Microarc Oxidation of Aluminum Alloys', Physics and Chemistry of Materials Treatment, 1991, 25 (5) pp. 580-582, 1991, month not available.
V. N. Kuskov et al., 'Phase Composition and Microhardness of Coatings Produced by Microarc Oxidation', Fizika i Khimiya Obrabotki Materialov, vol. 24, No. 6, pp. 101-103, 1990, month not available.

(List continued on next page.)

Primary Examiner—Kathryn Gorgos
Assistant Examiner—William T. Leister(57) **ABSTRACT**

A process and apparatus for forming oxide coatings on bodies of aluminum and aluminum alloys are described. The process includes forming an electrolyte bath in an inert container. At least two reactive metal bodies are suspended in the bath. The bodies are connected to electrodes which, in turn, are connected to a multiphase AC circuit. A multiphase power (preferably three-phase between three bodies) potential is imposed between each of the bodies. The bodies are moved in the electrolyte bath relative to each other until micro-arcs occur on the surfaces of the bodies, whereby the micro-arc oxidation of the bodies. The imposition of the potential between each of the bodies is continued until the desired thickness of oxide is formed on the bodies.

30 Claims, 2 Drawing Sheets



	Document ID	Pages	U	S	C	P	Kind Codes	Sort
24	US 5354390 A	5	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT	
25	US 5344551 A	17	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT	
26	US 5296260 A	19	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT	
27	US 5281326 A	3	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT	
28	US 5217597 A	6	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT	
29	US 5205921 A	4	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT	
30	US 5147515 A	3	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT	

US-PAT-NO: 5147515

DOCUMENT-IDENTIFIER: US 5147515 A

TITLE: Method for forming ceramic films by anode-spark discharge

----- RWIC -----

Brief Summary Text - BPTX (35):

Low outgassing properties, corrosion resistance and fastness properties can be imparted to an apparatus for manufacturing semiconductor devices by applying a ceramic film onto the shroud or the chamber of a reaction vessel of the apparatus according to the method of this invention. Moreover, if an aluminum or aluminum clad copper conductors is provided with a ceramic coating, there can be obtained an electric wire coated with the ceramic layer having high dielectric breakdown voltage in addition to high flexibility and whose coated layer is hardly broken even if the layer has a flaw.

Current US Cross Reference Classification - CCXR (1):
205/320Current US Cross Reference Classification - CCXR (2):
205/321Current US Cross Reference Classification - CCXR (3):
205/322Current US Cross Reference Classification - CCXR (4):
205/323

United States Patent [19] Hanagata et al.

US005147515A

[11] Patent Number: 5,147,515

[43] Date of Patent: Sep. 15, 1992

3,946,676 6/1976 Miyawata et al. 205/723

FOREIGN PATENT DOCUMENTS

151330 10/1981 Fed. Rep. of Germany
156003 7/1982 Fed. Rep. of Germany

Primary Examiner—John Niebling

Assistant Examiner—Brian M. Bolan

Attorney, Agent, or Firm—Obton, Spivak, McClelland,

Maker & Neundorfer

[57]

ABSTRACT

A method for forming a ceramic film on the surface of a substrate comprises performing spark discharge in an electrolytic bath, wherein the electrolytic bath comprises an aqueous solution of a water-soluble or colloidal silicate and/or an oxyacid salt to which ceramics fine particles and/or specific fine particles are dispersed and the spark discharge is carried out in the electrolytic bath while ensuring the suspended state of the ceramics particles and/or the specific fine particles in the electrolytic bath. The method makes it possible to effectively form, on the surface of a metal substrate, ceramics films having a variety of color tones as well as excellent insulating properties and hardness. Moreover, it further makes it possible to effectively form a composite ceramics film having excellent wear resistance on the surface of a metal substrate.

13 Claims, No Drawings

[54] METHOD FOR FORMING CERAMIC FILMS
BY ANODE-SPARK DISCHARGE

[75] Inventors: Haruo Hanagata, Ebioka, Tetsuo
Sumitani, Kazuo Yasegata, both of
Kaukabu, Hidetsugu Iguchi, Tokyo,
all of Japan

[73] Assignee: Dipsol Chemicals Co., Ltd., Tokyo,
Japan

[21] Appl. No.: 573,703

[22] Filed: Aug. 28, 1990

[30] Foreign Application Priority Data

Sep. 4, 1989 [JP] Japan 1-218639

Mar. 4, 1990 [JP] Japan 2-54837

[31] Int. Cl.³ H05F 3/04

[32] U.S. Cl. 205/321; 205/322; 205/323

[38] Field of Search 205/321, 322, 323, 320

204/164; 427/37; 106/638, 639, 637; 264/722

References Cited

U.S. PATENT DOCUMENTS

3,812,021 5/1974 Craig et al. 204/38

3,812,022 5/1974 Craig et al. 204/38

3,812,023 5/1974 Hradcovsky et al. 204/384

3,996,000 5/1976 Hradcovsky et al. 204/384

see next sheet
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Document ID	Pages	U	S	C	P	Kind	Codes	Source
11 US 5723038 A	4	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
12 US 5385662 A	4	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
13 US 5344551 A	17	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
14 US 5290592 A	20	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
15 US 5290424 A	14	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
16 US 5268045 A	15	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
17 US 5225069 A	7	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT

US-PAT-NO: 5225069

DOCUMENT-IDENTIFIER: US 5225069 A

TITLE: Process for the production of oxide ceramic surface films on silicon-containing light metal cast alloys

----- KWIC -----

Brief Summary Text - B9TX (5):

It is known to produce high-adhesion, dense and thick dispersion films on metals, especially on iron and iron work materials, by means of anodic elec-discharge or conventional thermal treatment by deposition from dispersion systems (DD-P8 151330).

Current US Original Classification - CCOR (1):

205/325

Current US Cross Reference Classification - CCXR (1):

205/332

United States Patent

Haupt et al.

[19]

US005225069A

[11] Patent Number: 5,225,069

[43] Date of Patent: Jul. 6, 1993

[54] PROCESS FOR THE PRODUCTION OF OXIDE CERAMIC SURFACE FILMS ON SILICON-CONTAINING LIGHT METAL CAST ALLOYS

[56] References Cited

FOREIGN PATENT DOCUMENTS

23399 2/1991 Japan

Primary Examiner—T. M. Tufarillo
Attorney, Agent, or Firm—McAulley Fisher Nissen
Goldberg & Kiel

[57] ABSTRACT

A process for the production of white and black oxide ceramic surface films on silicon-containing light metal cast alloys by plasma-chemical anodic oxidation. An aluminum cast alloy is pickled with nitric acid and by-drofluoric acid and coated by plasma-chemical anodic oxidation in an aqueous electrolyte. Accordingly, a coating variant is provided particularly for construction parts of silicon-containing light metal cast alloy having complicated shapes which enables the production of uniformly thin oxide ceramic surface films in contrast to conventional coating variants.

8 Claims, 3 Drawing Sheets

[75] Inventors: Kereth Haupt, Jürgen Schmidt;
Ulrich Bayer; Thomas Pöschel, all of
Jena, Fed. Rep. of Germany

[73] Assignee: Joseph GbH, Jena, Fed. Rep. of
Germany

[21] Appl. No.: 84,691

[22] Filed: May 18, 1992

[30] Foreign Application Priority Data

May 21, 1991 [DE] Fed. Rep. of Germany 4116910

[31] Int. Cl. C23D 11/16

[32] U.S. Cl. 205/325; 205/332

[36] Field of Search 205/323, 332

AlSi 120

DISTRIBUTION=

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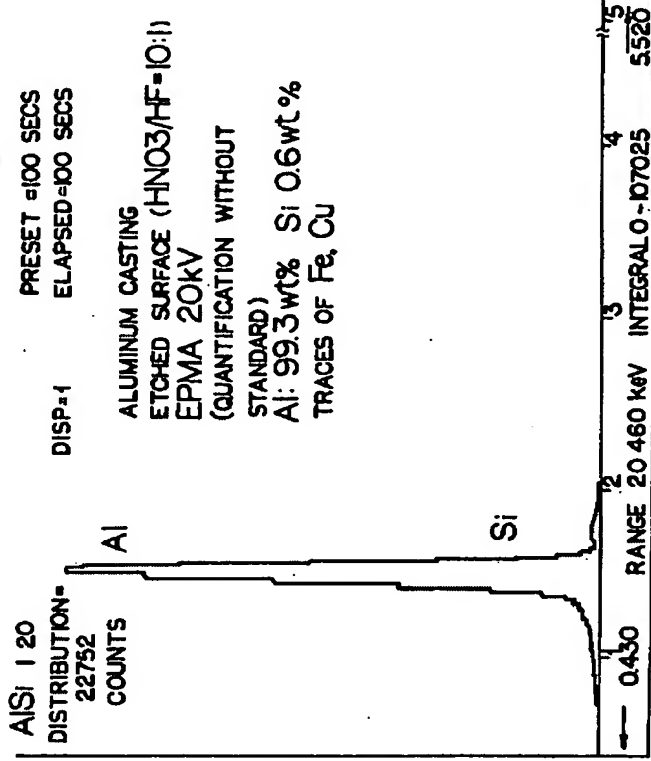
COUNTS

DISP=1

PRESET =100 SECS

ELAPSED=100 SECS

ALUMINUM CASTING
ETCHED SURFACE (HNO3/HF=10:1)
EPMA 20KV
(QUANTIFICATION WITHOUT
STANDARD)
Al: 99.3 wt% Si 0.6 wt%
TRACES OF Fe, Cu



9/2003 10/018709

all 5.17 pulsed current 200-1000 Hz

2 EAST - Deliauti EAST Workspace [Flat Panel LANDSCAPE.wsp |] Edit View Edit Tools Window Help

<div style="float: left; width: 80%;"> <p>Drafts</p> <ul style="list-style-type: none"> - [X] Pending - [X] Active - [X] L1: (14562) (205/50-333).CCLIS. - [X] L2: (6313) (arc or arcs) near2 plasma - [X] L3: (3) (microarc or microarcs) near2 plasma - [X] L4: (6316) L2 or L3 - [X] L5: (36) L4 and L1 - [X] L6: (3949) ceramic adj coating - [X] L7: (59) L1 and L6 - [X] L8: (15154) arc same discharge - [X] L9: (32) L1 and L8 - [X] L12: (3205) spark adj discharge - [X] L13: (29) L1 and L12 - [X] Failed - [X] Saved - [X] Favorites - [X] Tagged (0) - [X] UDC - [X] Queue - [X] Trash </div> <div style="float: right; width: 15%; text-align: right;"> <input type="checkbox"/> Draft <input checked="" type="checkbox"/> Highlight all hit terms initially </div>						<div style="float: left; width: 80%;"> <p>DB1 JSPAL USFQUB</p> <p>Default operator: OR</p> <p>L1 and L12</p> </div> <div style="float: right; width: 15%; text-align: right;"> <input type="button" value="Search"/> <input type="button" value="Loc"/> <input type="button" value="Browse"/> <input type="button" value="Queue"/> <input type="button" value="Clear"/> </div>								
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Document ID	Pages	U	S	C	P	Kind Codes	Source
1 US 6524716 B1	4	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
2 US 6487969 B2	6	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
3 US 6368467 B1	7	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
4 US 6365028 B1	6	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
5 US 6358391 B1	7	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT
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7 US 5720866 A	9	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		USPAT

US-PAT-NO: 6365028

DOCUMENT-IDENTIFIER: US 6365028 B1

TITLE: Method for producing hard protection coatings on articles made of aluminum alloys

----- RWIC -----

Brief Summary Text - BSTR (9):

A method is known for applying solid corrosion-resistant coatings to items made of aluminum and its alloys (U.S. Pat. No. 5,275,713) in an aqueous electrolyte solution containing an alkaline metal silicate, hydrogen peroxide and small quantities of hydrogen fluoride, alkaline metal hydroxide and a metal oxide (for example, molybdenum oxide). The solution has a pH of 11.2-11.8. A positive potential is delivered to the item from a direct or pulsed current source. For the first 1-60 s the voltage is raised to 240-260 V, and over the next 1-20 minutes (depending on the required coating thickness) it is steadily increased to 380-420 V. The introduction of hydrogen peroxide as an oxygen accumulator into the electrolyte helps to raise the rate of increase of the oxide coating and its hardness through intensification of oxide coating of the metal in the spark discharge zone.

Brief Summary Text - BSTR (17):

The oxide coating time may not be shortened by raising the electrical parameters of the electrolysis, for example the current density (above 30 A/dm²), because of a deterioration in the quality of the coating and a steep rise in the energy consumption of the process. The time of transition from the anodizing stage to the spark discharge stage, however, depends on the initial current density.

Current US Original Classification - CCOR (1): 205/102

Current US Cross Reference Classification - CCXR (1): 205/103

Current US Cross Reference Classification - CCXR (2): 205/106

Current US Cross Reference Classification - CCXR (3): 205/323

Current US Cross Reference Classification - CCXR (4): 205/326

(12) United States Patent

Shatrov

 (10) Patent No.: US 6,365,028 B1
 (45) Date of Patent: Apr. 2, 2002

(34) METHOD FOR PRODUCING HARD PROTECTION COATINGS ON ARTICLES MADE OF ALUMINUM ALLOYS

(75) Inventor: Alexander Sergeevich Shatrov, Moscow (RU)

(73) Assignee: Isle Coat Limited (GB)

(*) Notice: Subject to any disclaimer, the term of this patent is extended or adjusted under 35 U.S.C. 154(b) by 0 days.

(21) Appl. No.: 09/581,494

(22) PCT Filed: Dec. 17, 1997

(86) PCT No.: PCT/RU97/00408

§ 371 Date: Jun. 14, 2000

§ 102(e) Date: Jun. 14, 2000

(87) PCT Pub. No.: WO99/31303

PCT Pub. Date: Jun. 24, 1999

(51) Int. Cl. 7

(52) U.S. Cl.

(58) Field of Search

(56) References Cited

U.S. PATENT DOCUMENTS

 5,066,368 A * 11/1991 Pasqualoni et al. 205/112
 5,275,713 A 1/1994 Khrushchovskiy 205/106

FOREIGN PATENT DOCUMENTS

 RU 1200591 4/1989
 RU 1713990 2/1992
 RU 94023296 10/1996
 RU 2070623 12/1996
 RU 2070947 12/1996
 WO 95/518250 7/1995

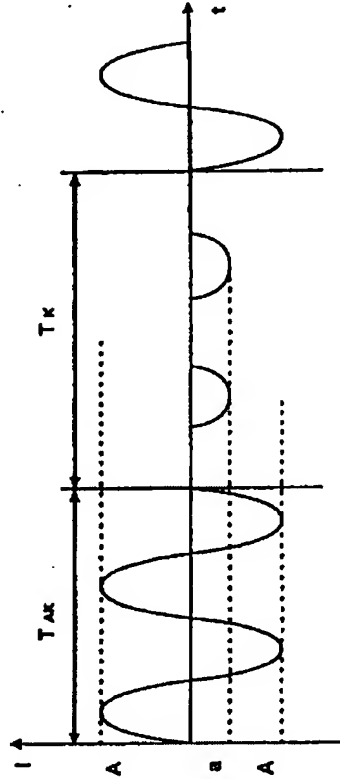
* cited by examiner

 Primary Examiner—Kathryn Gorgos
 Assistant Examiner—Wesley A. Nicolas
 (74) Attorney, Agent, or Firm—Shendin Ross P.C.

ABSTRACT

This invention relates to the sphere of plasma electrolytic oxide coating of aluminum alloys. The method incorporates anode-cathode oxide coating in an alkaline electrolyte at a temperature of 15–50° C, using 50–60 Hz frequency alternating current. In the initial stage of the process oxide coating is carried on for 5–90 seconds at a current density of 160–180 A/dm², then the current density is dropped to 3–30 A/dm² and the process is continued in a regime of spontaneous diminution of power demand without on-line adjustment of the regime until the set coating thickness is achieved. The alkaline electrolyte used is an aqueous solution of alkaline metal hydroxide at 1–5 g/l, an alkaline metal silicate at 2–15 g/l, an alkaline metal pyrophosphate at 2–20 g/l and peroxide compounds at 2–7 g/l (in terms of H₂O₂—30%). The method enables the protective properties of ceramic oxide coatings to be enhanced through an increase in the micro-hardness, density and strength of adhesion to the substrate without any additional energy outlay or time required.

4 Claims, 1 Drawing Sheet



Document ID	Pages	U	S	C	P	Kind Codes	Source
1 US 6368467 B1	7	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT
2 US 5981084 A	13	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT
3 US 5958604 A	17	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT
4 US 5700366 A	12	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	USPAT
5 US 20030085113 A	15	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US-PGPH

US-PAT-NO: 5958604

DOCUMENT-IDENTIFIER: US 5958604 A

See image for Certificate of Correction

TITLE: Electrolytic process for cleaning and coating electrically conducting surfaces and product thereof

----- KWIC -----

INVENTOR - INNOM (2):
 Stebilenko, Valerij L.

United States Patent

Riabkov et al.

[19]

[11] Patent Number: 5,958,604

[45] Date of Patent: *Sep. 28, 1999

[54] ELECTROLYTIC PROCESS FOR CLEANING AND COATING ELECTRICALLY CONDUCTING SURFACES AND PRODUCT THEREOF

[75] Inventors: Vitalij M. Riabkov, Moscow, Valerij L. Stebilenko, Magnitogorsk, both of Russian Federation

[73] Assignee: Metal Technology, Inc., Mandeville, La.

[*] Notice: This patent is subject to a terminal disclaimer.

[21] Appl. No.: 08/934,553

[22] Filed: Sep. 22, 1997

Related U.S. Application Data

[63] Continuation-in-part of application No. 08/705,914, Sep. 3, 1996, Pat. No. 5,700,366.

[30] Foreign Application Priority Data

Mar. 20, 1996 [RU] Russian Federation 96104583

[51] Int. Cl.⁶ C25D 5/08

[52] U.S. Cl. 428/612; 205/87; 205/95; 205/102; 205/131; 205/148; 205/151; 205/219; 428/687; 428/935

[58] Field of Search 205/131, 148, 151, 219, 705, 712, 714, 715, 716; 428/612, 687, 935

[56] References Cited

U.S. PATENT DOCUMENTS

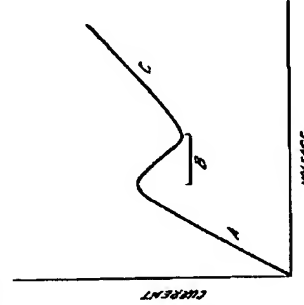
3,620,934 11/1971 Endie 205/87
 3,854,999 9/1974 Hradovsky et al. 205/318
 4,504,041 12/1981 Grindia et al. 205/96

(List continued on next page.)

FOREIGN PATENT DOCUMENTS

1165271 4/1984 Canada
 0037190 10/1981 European Pat. Off.

25 Claims, 7 Drawing Sheets



A.V. Timoshenko et al., "The Effect of Silicates in Sodium-Hydroxide Solution... by Microarc Oxidation" in *Protection of Metals*, vol. 30, No. 2, 1944, pp. 175-180. No Month Available.

Primary Examiner—Kathryn Googes
 Assistant Examiner—William T. Leeder
 Attorney, Agent, or Firm—Watson Cole Grindie Watson, PLLC.

[57] ABSTRACT

An electrolytic process for metal-coating the pre-cleaned surface of a workpiece of an electrically conducting material, which process comprises:

- providing an electrolytic cell with a cathode comprising the workpiece and an anode comprising the metal for metal-coating of the surface of the workpiece;
- introducing an electrolyte into the zone created between the anode and the cathode by causing it to flow under pressure through at least one opening in the anode impinge on the cathode; and
- applying a voltage between the anode and the cathode and operating in a regime in which the electrical current decreases or remains substantially constant with increase in the voltage applied between the anode and the cathode, and in a regime in which discrete gas bubbles are present on the surface of the workpiece during treatment.

